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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

IN RE APPLICATION OF:

Kohei KAWAMURA, et al.

SERIAL NO: 10/567,733

GROUP: 2812

FILED: February 10, 2006

EXAMINER:

FOR: METHOD FOR FORMING FILM, METHOD FOR MANUFACTURING  
SEMICONDUCTOR DEVICE, SEMICONDUCTOR DEVICE AND  
SUBSTRATE TREATMENT SYSTEM

**LETTER**

Mail Stop DD  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Submitted herewith is a Korean Office Action for the Examiner's consideration. The reference cited therein has been previously filed on February 10, 2006.

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND,  
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